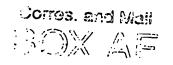
Appln. No. 10/621,497 Response dated February 15, 2006 Reply to Office Action dated December 7, 2005





2/V/06



**RESPONSE UNDER 37 CFR 1.116** EXPEDITED PROCEDURE **EXAMINING GROUP 1765** 

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Applicant** 

Tetsuhiro Iwai, et al.

Appln. No.

10/621,497

Filed

July 17, 2003

Title

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PROCESSING METHOD

Conf. No.

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TC/A.U.

1765

Examiner

Lan Vinh

Customer No.

000,116

Docket No.

35908

Mail Stop AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

## **RESPONSE "C"** AFTER FINAL UNDER RULE 1.116

Sir:

This communication is filed in response to the Office Action dated December 7, 2005 (Paper No. 120105). The three-month period for responding to the Office Action expires on March 7, 2006.

The following remarks are made for the Examiner's consideration.

Remarks/Arguments begin on page 2 of this paper.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date indicated below. Suzanne B. Gagnon Name of Attorney for Applicant(s)